

Notice of References Cited		Application/Control No. 10/522,688	Applicant(s)/Patent Under Reexamination CHOQUET ET AL.	
		Examiner Mark L. Shevin	Art Unit 1793	Page 1 of 1

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*	Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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*	B US-5,397,652	03-1995	Carey et al.	428/610
*	C US-4,940,522	07-1990	Kagechika et al.	204/192.1
*	D US-5,073,403	12-1991	Kagechika et al.	427/528
*	E US-5,270,081	12-1993	Manier et al.	427/534
*	F US-5,397,652	03-1995	Carey et al.	428/610
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a))
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